

ABSTRACT

A micro-mirror element includes a micro-mirror substrate, a wiring substrate and an electroconductive spacer disposed between the two substrates. The micro-mirror substrate is formed integral with a frame, a moving portion having a mirror portion, and a torsion bar connecting the frame to the moving portion. The wiring substrate is provided with a wiring pattern. The electroconductive spacer separates the micro-mirror substrate from the wiring substrate and also electrically connects the frame to the wiring pattern. The wiring substrate has a surface that faces the micro-mirror substrate. A detector is provided on this surface for detecting the pivot angle of the mirror portion.